

Amendments to the Specification:

Please replace the paragraph beginning on page 4, line 4, with the following amended paragraph:

Figure 6 is a feature from the sample embodiment of a printing or copying machine in the region of a fixation device, ~~and ; and~~

Please replace the paragraph beginning on page 8, line 1, with the following amended paragraph:

Figure 3 shows another sample embodiment of the fixation device 3, namely, a heating device 13, which includes a microwave resonator 49. This has a ~~slitlike~~ slit-like opening 51, through which the substrate 5 is guided in the direction of transport 11. There is a first pressure chamber 53 integrated into the portion of the microwave resonator 49 lying underneath the transport path of the substrate 5, which extends transversely across the width of the substrate's transport path and has an opening 55 facing the substrate's transport path, which is covered with a perforated plate 57. The perforated plate 57 has a number of through openings and/or slots that function as nozzles when pressure is applied from the first pressure chamber 53, as shall be discussed further below. The perforated plate 57 is made from a material with low microwave absorption, in order that the resulting heating be slight. The material is chosen so that, allowing for the cooling air flow, the temperature of the perforated plate is not more than 50°C to 100°C (depending on the melting temperature of the toner used). In this way, one can prevent toner dust from sticking to the perforated plate with the occasionally resulting clogging of holes. Examples of materials for the perforated plate are fluoropolymers, such as PVDF (polyvinylidene fluoride), or PTFE (polytetrafluorethylene), or technical grade ceramics like silicate ceramics, oxide ceramics (e.g., aluminum oxide), or nonoxide ceramics.

Please replace the paragraph beginning on page 9, line 6, with the following amended paragraph:

Therefore, sufficient pressurized air is applied to the substrate 5 by the first pressure chamber 53 and the perforated plate 57, so that it floats almost weightlessly above the lower part of the microwave resonator 49. The strength of the air cushion is adjusted so that the distance between the substrate 5 and the upper perforated plate 63 is at least so large that a jamming of the substrate inside the ~~slitlike~~ slit-like opening 51 is prevented. In this sample embodiment (as mentioned), a second pressure chamber 59 is provided in the upper part of the microwave resonator 49, by which a second air cushion can be created between the substrate topside 9 and the upper part of the microwave resonator 49. In this way, any contact between the substrate 5 and the perforated plate 63 can be virtually excluded. In a sample embodiment not represented in the Figures, the second pressure chamber 59 is omitted and the free floating condition of the substrate 5 within the heating device 13 is accomplished entirely by the air cushion created by the first pressure chamber 52 on the underside 9 of the substrate 5.

Please replace the paragraph beginning on page 10, line 6, with the following amended paragraph:

Figure 4 shows another sample embodiment of the guide device 17, which here has a holding device 67 (not represented more precisely), by which the substrate 5 can be grabbed in the region of its front edge. By "grabbed" is meant that the holding device 67 holds the substrate 5 by friction and/or by form fitting. The holding device 67 here is arranged at the free end of at least one lever 71 which can pivot about an axis 69. The pivoting lever 71 is arranged near the microwave resonator looking in the transport direction of the substrate. The guide device 17 represented in Figure 4 is combined with a heating device 13 of the fixation device 3, which is essentially identical in construction to that described by Figure 3. One difference is

that, although the microwave resonator 49 has recesses to configure the first and second pressure chambers 53, 59, these are not connected to a pressurized air supply unit. Thus, no air cushion(s) is created in the ~~slitlike~~ slit-like opening 51 of the microwave resonator 49 in the sample embodiment.

Please replace the paragraph beginning on page 10, line 20, with the following amended paragraph:

In the position of the pivoting lever 71 represented in Figure 4, the front edge of the substrate 5, being carried from a portion of the machine arranged in front, to the heating device 13 is grabbed by the holding device 67. By a pivoting of the lever 71 in the clockwise direction about the axis 69, the substrate is carried along and follows the trajectory 73 of the holding device 67, which leads through the ~~slitlike~~ slit-like opening 51 in the microwave resonator 49. The substrate 5 is carried along in such a way that the substrate 5 has no mechanical contact with the microwave resonator 49 inside the opening 51. The broken line indicates the trajectory 75 of the substrate 5 inside the opening 51 of the microwave resonator 49. It should be noted that in this sample embodiment as well, the substrate 5 moves free floating in the effective range of the heating device 13, i.e., the microwave resonator 49.

Please replace the paragraph beginning on page 10, line 32, with the following amended paragraph:

Figure 5 shows a lengthwise section through a sample embodiment of the holding device 67, which comprises a strip 77 that when installed extends transverse to the direction of substrate transport 11. The strip 77 has a ~~slitlike~~ slit-like opening 79, which is connected to a partial vacuum device via a connection channel 81. Thus, the grabbing of the substrate 5 here occurs in such a way that a partial vacuum is applied to the opening 79, which sucks the substrate 5 to the strip 77 and holds it there as shown in Figure 5. The height h of the strip 77 is less than the height of the ~~slitlike~~ slit-like opening 51 in the microwave resonator 49, so that the strip 77 can be taken through the opening 51 without making contact.

Please replace the paragraph beginning on page 11, line 20, with the following amended paragraph:

In addition to or instead of the ~~slitlike~~ slit-like opening 79, the strip 77 can also have several suction openings formed by boreholes.

Please replace the paragraph beginning on page 13, line 30, with the following amended paragraph:

Figure 7 shows in perspective view a portion of a sample embodiment of the heating device 13 represented in Figure 6. This comprises a first microwave resonator 105, which is followed directly by a second microwave resonator 107. These each have a ~~slitlike~~ slit-like opening 109, extending transverse to the transport direction 6 of the substrate, through which the substrate 5 is taken free floating as described by Figure 3. As can be seen, the effective range of the microwave resonators 105, 107 looking down on the transport path of the substrate is very short or short. However, with such a heating device 13, a very high energy density can be transmitted to the substrate 5 without contact.